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APPLICANTS

Kazuo Nishimoto, Tokyo, JAPAN;

Tatsuaki Sakano, Tokyo, JAPAN;

Akihiro Takemura, Tokyo, JAPAN; Masayuki Hattori, Tokyo, JAPAN;

Nobuo Kawahashi, Tokyo, JAPAN;

Naoto Miyashita, Yokohama-shi, JAPAN;

Atsushi Shigeta, Fujisawa-shi, JAPAN;

Yoshitaka Matsui, Yokohama-shi, JAPAN;

Kazuhiko Ida, Yokohama-shi, JAPAN;

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YES MM

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Verified and Acknowledged	<i>MM</i> Examiner's Signature Initials	JAPAN	0	23	3

ADDRESS

22850

OBLON, SPIVAK, MCCLELLAND, MAIER & NEUSTADT, P.C.

1940 DUKE STREET

ALEXANDRIA, VA

22314

TITLE

Aqueous dispersion for chemical mechanical polishing, chemical mechanical polishing process, production process of semiconductor device and material for preparing an aqueous dispersion for chemical mechanical polishing